

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	)
Tadashi MITSUI	) Group Art Unit: 2624
Application No.: 10/807,187	) Examiner: David RASHID
Filed: March 24, 2004	)
For: PATTERN MEASURING APPARATUS, PATTERN MEASURING METHOD, AND MANUFACTURING METHOD OF SEMICONDUCTOR DEVICE	) Confirmation No.: 3737 ) ) )

## Mail Stop RCE

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

## **AMENDMENT**

This Amendment is being filed concurrently with a Request for Continued Examination under 37 C.F.R. § 1.114, and in reply to the final Office Action mailed September 7, 2007, the period for response to which extends through December 7, 2007. Applicant respectfully requests reconsideration of this application in view of the following amendments and remarks.